Supplementary Information

Phase-pure antiferroelectric AgNbO₃ films on Si substrates: chemical solution deposition and phase transitions

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*Corresponding author. E-mail: Jing-Feng Li: jingfeng@mail.tsinghua.edu.cn Lisha Liu: net4663@126.com Qian Li: qianli_mse@tsinghua.edu.cn 1. The evidence of hypothesis stabilization mechanism



Fig. S1 Fourier transform infrared (FTIR) spectroscopy of (a) 2-MOE+CA solution; (b) 2-MOE+CA+EG solution; (c) 2-MOE+CA+EG+M' solution, where M' denotes metal salt or metal alkoxide, here meaning AgNO₃ and Nb(OCH₂CH₃)₅.

FT-IR spectroscopy has been considered to be one of the powerful spectroscopic tool for the detemination of funcational groups in the organic solution to study and understand the reaction machanisms.¹ We designed three groups of solutions : "2-MOE+CA" group as control group, "2-MOE+CA+EG" as the experimental group to investigate the esterification reaction between EG and CA, and "2-MOE+CA+EG+M'" as the other experimental group to confirm the chelating reaction between metal ions with CA. As shown in Fig. S1, in "2-MOE+CA" solution, the characteristic peak at 1730 cm⁻¹ has been assigned to carbonyl C=O stretching mode in the -COOH carboxylic-acid groups of CA. The shoulder peak at 1710 cm⁻¹ around the C=O peak (1730 cm⁻¹) results from the reaction between the -COOH in CA and -OH in 2-MOE. After introducing EG in the "2-MOE+CA" solution, the intensity of the shoulder peak at 1710 cm⁻¹ becomes more stronger, accompanied by the additional characteristic peaks for C-OH mode between 1000 cm⁻¹ and 1100 cm⁻¹, suggesting the more esterification reaction happens between -OH in EG and -COOH in CA to form the organic network. With further adding metal salt or metal alkoxide (M', denoting AgNO₃ and Nb(OCH₂CH₃)₅) in "2-MOE+CA+EG" solution, the absorbance peak at 1565 cm⁻¹ characterized by the -COOM group evidences the chelating effect of -COOH in CA. Meanwhile, the peak occurring at 1667 cm⁻¹ denotes the formation of R-NO₂, indicating the incorporation of NO₃⁻ in AgNO₃ into the organic network.

2. Texture discussion



Fig. S2 The annealing temperature and thickness dependence of (100) texture coefficient of 5-layer AgNbO₃ films pyrolyzed at 450 °C compared with PDF card of AgNbO₃ (JCPDS file No. 70-4738)

For CSD, film texturing is often observed depending on the annealing temperature and substrate.^{1–5} Here, in 5-layer AgNbO₃ films pyrolyzed at 450 °C, {100} texturing development (here the orientation of (200) dominates) is observed with increasing annealing temperature. The texture coefficient is calculated from the peak intensity using the following equation:

$$\alpha_{\{100\}} = \frac{I_{(100)} + I_{(200)}}{\sum I_{(hkl)}} \tag{1}$$

where α denotes the texture coefficient, *I* represents the integration intensity of XRD peaks of AgNbO₃ phase, and the subscripts denote the peak index. The texture coefficient is significantly increased from 28% to 45% as the annealing temperature increases from 650 °C to 750 °C, suggesting higher annealing temperature promotes heterogeneous nucleation and grain growth of AgNbO₃ (200) on the surface of Pt/Ti/SiO₂/Si substrate. With further increasing the film thickness (i.e., 10-layer films annealing at 750 °C), heterogeneous nucleation of AgNbO₃ (200) is reduced which can be seen from the significantly decreased texture coefficient to 24% in 10-layer AgNbO₃ films, as shown in the **Fig. S2**, indicating the heterogeneous nucleation gradually turns to homogenous nucleation due to reduced heterogeneous interface effect.

3. Raman spectrum for determining oxygen vacancies



Fig. S3 Room-temperature Raman shift of the as-prepared 10-layer AgNbO₃ film ranging from 100 cm⁻¹ to 1000 cm⁻¹

The oxygen vacancies have also been characterized by Raman spectra, where the peak around 828 cm⁻¹ is the signal for adsorbed oxygen species at the surface.^{6–9} Additionally, for perovskite structure, there is an extra strong peak at 890 cm⁻¹, reflecting the existence of more oxygen vacancies for the as-prepared AgNbO₃ films, corresponding to the XPS fitting.

4. Quantitative EDS results



Fig. S4 (a)-(c) SEM images with different selected areas (purple rectangular) for element quantitative analysis; (d)-(f) quantitative EDS results of the as-prepared 10-layer AgNbO₃ film corresponding to the selected areas.

5. Temperature-dependent XRD measurement



Fig. S5 (a) The temperature-dependent XRD patterns of the phase-pure AgNbO₃ film from -70 °C to 300 °C; the inset: the peak position of AgNbO₃ (200) as a function of temperature. (b) The enlarged figure of AgNbO₃ (200) peak as a function of temperature.

The temperature-dependent XRD analysis has been also conducted to investigate phase transition between M (M₁, M₂, and M₃) phases from -70 °C to 300 °C under N₂ atomosphere, where no secondary phases have been detected as shown in **Fig S5 (a)**. The enlarged (200) peaks in **Fig. S5(b)** shows obvious peak shifting towards a lower angle with increasing temperature, suggesting the tendency of the increased lattice parameter along *c* axis. Howerer, there is an anomaly between -50 °C to -25 °C as shown in the inset of **Fig. S5 (a)**, corresponding to the phase transition temperature range of M₁-M₂ determined by temperature-dependent dielectric permittivity in **Fig. 5(b)**. This indicates that the lattice parameter along *c* axis first has a sudden decrease and then increases when entering M₂ phase from M₁, which may be due to the change of space group symmetry (probably from Pmc2₁ and Pbcm) between the two phases. Such lattice parameter changing behavior can also be observed in Li doped AgNbO₃ ceramics during the transition between two polar phases (P2₁am/R3c) to the antiferroelctric Pbnm phase.¹⁰ For comparison, relatively smaller change assocciated with the proposed M₂ and M₃ transition suggests less difference between the phase structure of M₂ and M₃.

6. Temperature-insensitive dielectric permittivity with low loss



Fig. S6 The temperature-dependent dielectric permittivity and loss of the phase-pure AgNbO₃ films from 150 °C to 350 °C measured at 100 kHz and 1 MHz.

Table S1 The dielectric properties of the as-prepared AgNbO₃ films compared with other Ag(Nb,Ta)O₃ films measured at 100 kHz at both higher temperature (HT) and room temperature (RT).

Film	Substrate	Er (High T)	tanδ (High T)	Er (RT)	tanð (RT)	Ref
$(00l) \operatorname{Ag}(\operatorname{Nb}_{0.5}\operatorname{Ta}_{0.5})O_3$	(001)SRO/LAO	275±25 (150~290 °C)	0.025~0.037	357	0.020	11,12
$(00l)Ag_2(Nb_{0.5}Ta_{0.5})_4O_{11}$	(111)Pt/Ti/SiO ₂ /Si	104±1 (150~200 °C)	0.021~0.037	118	0.004	13
* Ag(Nb _{0.5} Ta _{0.5})O ₃	(111)Pt/Ti/SiO ₂ /Si	210±8 (150~200 °C)	0.028~0.043	250	0.004	13
AgNbO ₃	(111)Pt/Ti/SiO ₂ /Si	416±14 (150~350 °C)	0.006~0.042	315	0.020	This
(100 kHz)						Work
AgNbO ₃	(111)Pt/Ti/SiO ₂ /Si	408±12 (150~350 °C)	0.008~0.032	312	0.015	This
(1 MHz)						Work

* Mostly perovskite Ag(Nb_{0.5}Ta_{0.5})O₃ with little natrotantite secondary phase

7. Seebeck coeffient measurement



Fig. S7 The Seebeck coeffient testment results of the film surface at 400 °C

Seebeck coefficient was tested by portable Seebeck tester (PTM-3, JouleYacht, China) at 400 °C on the hot plate with probes contacting the surface of films. As shown in the **Fig. S7**, the nagtive Seebeck coefficients are shown after testing for three times at different places, indicating that the main excited carriers are electrons. Therefore, we reasonably infer that the free carrier of the film is the electron.



8. Cross-section EDS maping in TEM mode

Fig. S8 (a) The bight-field TEM image of the cross-section of film and substrat (b)-(e) EDS mapping results of elements of Pt, Ti, Ag and Nb, respectively.

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